

# INTERNATIONAL SEARCH REPORT

International Application No

PCT/EP2004/014219

## A. CLASSIFICATION OF SUBJECT MATTER

IPC 7 G03F7/20

According to International Patent Classification (IPC) or to both national classification and IPC

## B. FIELDS SEARCHED

Minimum documentation searched (classification system followed by classification symbols)

IPC 7 G03F

Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched

Electronic data base consulted during the international search (name of data base and, where practical, search terms used)

EPO-Internal

## C. DOCUMENTS CONSIDERED TO BE RELEVANT

Category *	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
A	US 2003/174408 A1 (ROSTALSKI HANS-JUERGEN ET AL) 18 September 2003 (2003-09-18) paragraphs '0025!', '0057!; table 1	1-24
A	HOFFNAGLE J A ET AL: "Liquid immersion deep-ultraviolet interferometric lithography" JOURNAL OF VACUUM SCIENCE & TECHNOLOGY B: MICROELECTRONICS PROCESSING AND PHENOMENA, AMERICAN VACUUM SOCIETY, NEW YORK, NY, US, vol. 17, no. 6, November 1999 (1999-11), pages 3306-3309, XP012007924 ISSN: 0734-211X page 3307 - page 3308 NA=1.2, n(prism) = 1.5 < n(immersion) = 1.51 ----- -/-	1

☒ Further documents are listed in the continuation of box C.

☒ Patent family members are listed in annex

### \* Special categories of cited documents:

- \*A\* document defining the general state of the art which is not considered to be of particular relevance
- \*E\* earlier document but published on or after the international filing date
- \*L\* document which may throw doubts on priority claim(s) or which is cited to establish the publication date of another citation or other special reason (as specified)
- \*O\* document referring to an oral disclosure, use, exhibition or other means
- \*P\* document published prior to the international filing date but later than the priority date claimed

- \*T\* later document published after the international filing date or priority date and not in conflict with the application but cited to understand the principle or theory underlying the invention
- \*X\* document of particular relevance; the claimed invention cannot be considered novel or cannot be considered to involve an inventive step when the document is taken alone
- \*Y\* document of particular relevance, the claimed invention cannot be considered to involve an inventive step when the document is combined with one or more other such documents, such combination being obvious to a person skilled in the art.
- \*G\* document member of the same patent family

Date of the actual completion of the international search

25 May 2005

Date of mailing of the international search report

10/06/2005

Name and mailing address of the ISA

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## C.(Continuation) DOCUMENTS CONSIDERED TO BE RELEVANT

Category *	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No
P, X	<p>BRUCE SMITH: "Water-based 193nm immersion lithography" 'Online!  28 January 2004 (2004-01-28), XP002329291  Retrieved from the Internet:  URL: <a href="http://www.sematech.org/resources/litho/meetings/immersion/20040128/presentations/06%20RIT%20microstepper%20efforts_Smith.pdf">http://www.sematech.org/resources/litho/meetings/immersion/20040128/presentations/06%20RIT%20microstepper%20efforts_Smith.pdf</a>  ' retrieved on 2005-05-24!  page 14: NA &gt; 1, lens material: SiO<sub>2</sub>  page 22: n(liquid lens) &gt; 1.6 &gt; n(SiO<sub>2</sub>)</p> <p>-----</p>	1-24

**INTERNATIONAL SEARCH REPORT**

Information on patent family members

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PCT/EP2004/014219

Patent document cited in search report	Publication date	Patent family member(s)	Publication date
US 2003174408 A1	18-09-2003	DE 10210899 A1	18-09-2003
		AU 2002312872 A1	22-09-2003
		AU 2003221490 A1	22-09-2003
		WO 03077036 A1	18-09-2003
		WO 03077037 A1	18-09-2003
		EP 1483625 A1	08-12-2004
		EP 1485760 A1	15-12-2004
		US 2005030506 A1	10-02-2005
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